PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Gabriele Barlocchi et al. Filed : September 18, 2003

For : METHOD FOR FORMING HORIZONTAL BURIED

CHANNELS OR CAVITIES IN WAFERS OF MONOCRYSTALLINE SEMICONDUCTOR

MATERIAL

Docket No. : 854063.552D1

Date : September 18, 2003

Mail Stop Patent Application Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents:

In accordance with 37 C.F.R. §§ 1.56 and 1.97 through 1.98, applicants wish to make known to the Patent and Trademark Office the 13 references set forth on the attached Form PTO-1449. This application relies, under 35 U.S.C. § 120, on the earlier filing date of prior Application No. 09/545,260, filed April 7, 2000. The references listed on the attached Form PTO-1449 were submitted to and/or cited by the Patent and Trademark Office in this prior application and, therefore, are not required to be provided in this application. If the Examiner wishes, copies will be provided upon request. As to any reference supplied, applicants do not admit that it is "prior art" under 35 U.S.C. §§ 102 or 103, and specifically reserve the right to traverse or antedate any such reference, as by a showing under 37 C.F.R. § 1.131 or other method. Although the aforesaid references are made known to the Patent and Trademark Office in compliance with applicants' duty to disclose all information they are aware of which is believed relevant to the examination of the above-identified application, applicants believe that their invention is patentable.

Please acknowledge receipt of this Information Disclosure Statement and kindly make the cited references of record in the above-identified application.

Applicants believe this Information Disclosure Statement has been timely filed, however, the Commissioner is authorized to charge any fee due by way of this Information Disclosure Statement to our Deposit Account No. 19-1090.

Respectfully submitted,
Gabriele Barlocchi et al.
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ERTaep

Enclosures:

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Sheet <u>1</u> of <u>1</u>

FORM PTO-1449 (REV.7-80)					ATTY. DOCKET NO. AI 854063.552D1 APPLICANTS			APPLICATION NO.		
	INI	FORMATION DISCLOSURE (Use several sheets if nec			Gabriele Barlocchi et al. FILING DATE GROUP ART UNIT					
U.S. PATENT DOCUMENTS										
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE		NAME	CLA	SS	SUBCLASS	FILING IF APPRO	
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	AB	4,993,143	02/19/91	Sidner et al.		29		621.1		
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FOREIGN PATENT DOCUMENTS										
	DOCUMENT DA			COUNTRY					TRANSI YES	LATION NO
	AK	JP4114470 04/15/92 Japan (+abstract)								
	AL	JP9082983	082983 03/28/97 Japan							
	AM									
	AN									
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OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)										
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		Actuators, July 1992. Pages 51-57. Kovacs, Gregory T. A. et al., "Bulk Micromachining of Silicon", IEEE, August 1998. Vo.								
	AQ	86, No. 8, Pages 1536-1551.								
	AR	·								
EXAMINER DATE CONSIDERED										
* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).										